

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Mail Stop Patent Application
 Commissioner for Patents
 P.O. Box 1450
 Alexandria, VA 22313-1450



Re: Inventors: Siqing Lu, Yu Chang, Dongxi Sun, Vinh Dang, Michael X. Yang, Anzhong (Andrew) Chang, Anh N. Nguyen and Ming Xi
 Title: VALVE CONTROL SYSTEM FOR ATOMIC LAYER DEPOSITION CHAMBER

Transmitted herewith is the patent application identified above, including:

- ☒ Specification, claims and abstract, totaling 16 pages.
- ☒ Drawings totaling three pages, ☒ Formal ☐ Informal.
- ☒ Copy of Executed Declaration and Power of Attorney from parent application.
- ☐ Assignment of the invention to Applied Materials, Inc.
- ☐ Assignment Recordation Cover Sheet
- ☐ PTO Form 1449 and Information Disclosure Statement with no cited reference.
- ☒ Return Postcards

FEE CALCULATION					
Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	16	- 20 =	-0-	X \$18.00	\$0.00
Independent Claims	3	- 3 =	0	X \$80.00	\$0.00
Basic Filing Fee				\$710.00	\$710.00
TOTAL FEES					\$710.00

☐ The Commissioner is hereby authorized to charge \$710.00 to Deposit Account No. 50-1074.

☐ The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-1074. A duplicate copy of this transmittal is enclosed.

☒ Please address all future correspondence to:

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I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Mail Stop Patent Application, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Express Mail Receipt No. EL975549904US

Date of Deposit: December 9, 2003

Signature: 

Respectfully submitted,


 Brian M. Dugan
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